



# The Fringe Pattern of a Synchrotron-Light Interferometer

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Theory and Practice*

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# Derivation of the Interference Pattern

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- Assumptions:
  - One dimensional ( $y$ )
  - Two narrow, parallel slits of width  $a$
  - Small slit separation (center to center)  $d > a$
  - Slits are far from the source:  $z_{0s} \gg d$
  - Small source size  $\sigma_0$ , but comparable to slit width
  - Nearly monochromatic light, due to a bandpass filter



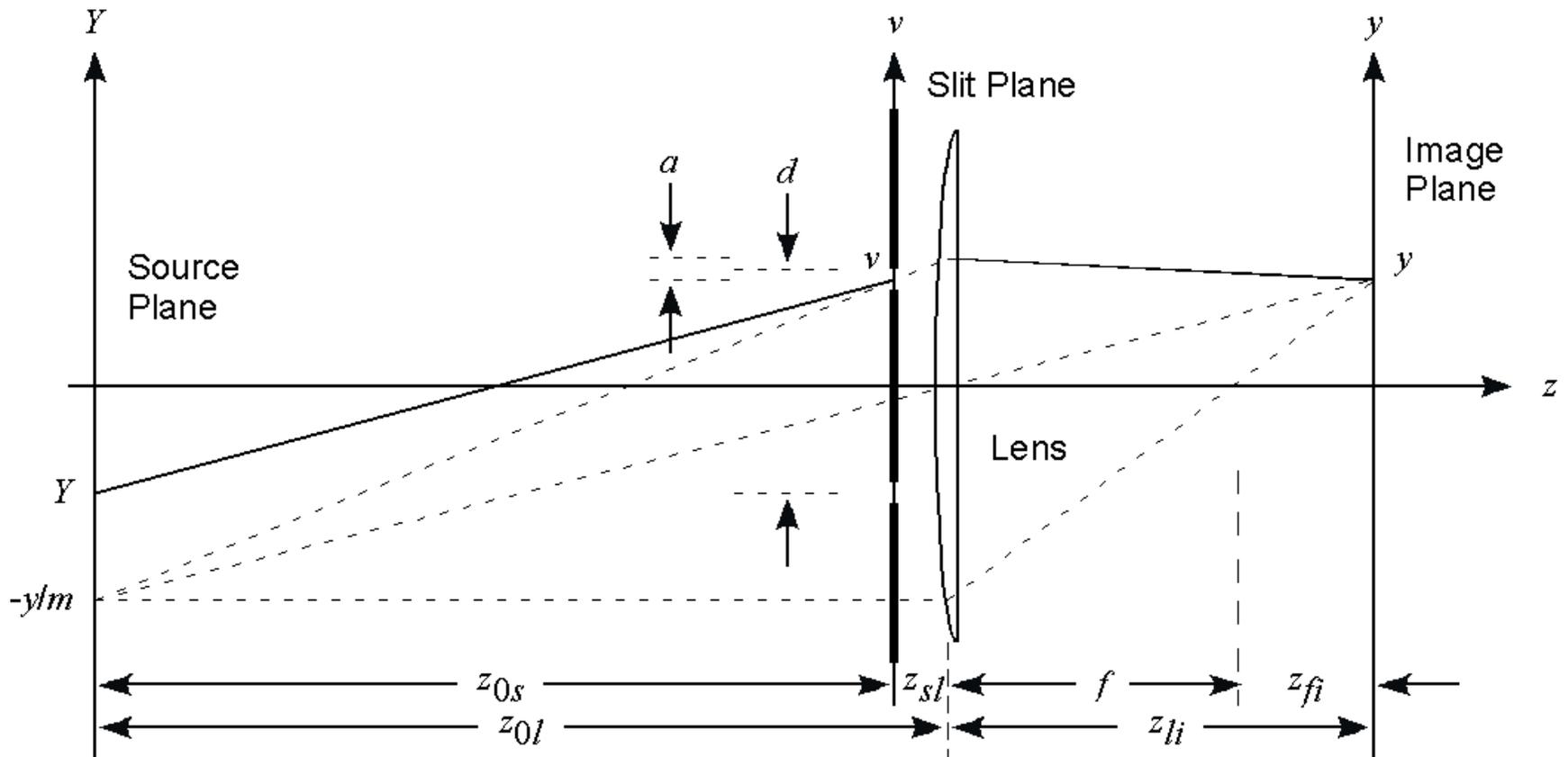
## Case 1: Monochromatic Point Source

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- Consider a point source at  $Y$  on the  $(X,Y)$  plane.
- The light is monochromatic, with  $\lambda = 2\pi/k$
- We calculate the intensity at a point  $y$  on the image plane  $(x,y)$ .
- The two slits are on the  $(u,v)$  plane.
- The electric field at  $y$  is found using a Fraunhofer diffraction integral over the slit plane.
  - We will need the difference in the length of the optical path for all the rays leaving  $Y$  and arriving at  $y$ .



# Layout of the Two-Slit Interferometer





# Reference Path

- Compare all paths to a reference path that:
  - Leaves the source plane at  $-y/m$ 
    - Here  $m$  is the magnification of the lens:  $m = z_{li}/z_{ol}$
  - Is imaged geometrically to  $y$  on the image plane.
- All paths from  $-y/m$  to  $y$  are *equal* in length.
  - A fundamental property of geometric imaging.
  - Applies to the imaged ray passing through the slit at  $v$ .
- Consider a ray leaving  $Y \neq -y/m$  that diffracts in the slit at  $v$  with an angle that brings it to  $y$ .
  - Its path matches the imaging path from  $-y/m$  to  $v$  to  $Y$  *after* the slit...but not before.
    - This lets us compute the path difference  $\Delta s$  from the reference.



# Difference in the Optical Path Length

$$\begin{aligned}\Delta s &= \sqrt{(v - Y)^2 + z_{0s}^2} - \sqrt{\left(v + \frac{z_{0l}}{z_{li}} y\right)^2 + z_{0s}^2} \\ &\approx \frac{1}{2z_{0s}} \left[ -2v \left( Y + \frac{z_{0l}}{z_{li}} y \right) + Y^2 - \left( \frac{z_{0l}}{z_{li}} y \right)^2 \right] \\ &= \frac{1}{2z_{0s}} \left[ -2v \left( Y + \frac{fy}{z_{fi}} \right) + Y^2 - \left( \frac{fy}{z_{fi}} \right)^2 \right] \\ &= -(gv + h)\end{aligned}$$

$$\text{where } \frac{1}{f} = \frac{1}{z_{0l}} + \frac{1}{z_{li}} = \frac{1}{z_{0l}} + \frac{1}{f + z_{fi}}$$



# Fraunhofer Diffraction Integral

$$E(y, Y, k) = \int_{\text{slits}} e(v) \frac{1}{s_{Y,v}} \exp \left[ iks_{Y,v} + iks_{v,y} \right] dv$$

$$= \int_{\text{slits}} \sqrt{A(v)} \exp \left[ ik\Delta s + i\phi(v) \right] dv$$

$$= ae^{-ikh} \operatorname{sinc} \left( \frac{kg a}{2} \right) \left( \sqrt{A_1} e^{-ikgd/2} + \sqrt{A_2} e^{ikgd/2 + i\phi_0} \right)$$

$$I(y, Y, k) = a^2 \operatorname{sinc}^2 \left( \frac{kg a}{2} \right) \left[ A_1 + A_2 + 2\sqrt{A_1 A_2} \cos(kgd + \phi_0) \right]$$

Envelope of  
single-slit diffraction

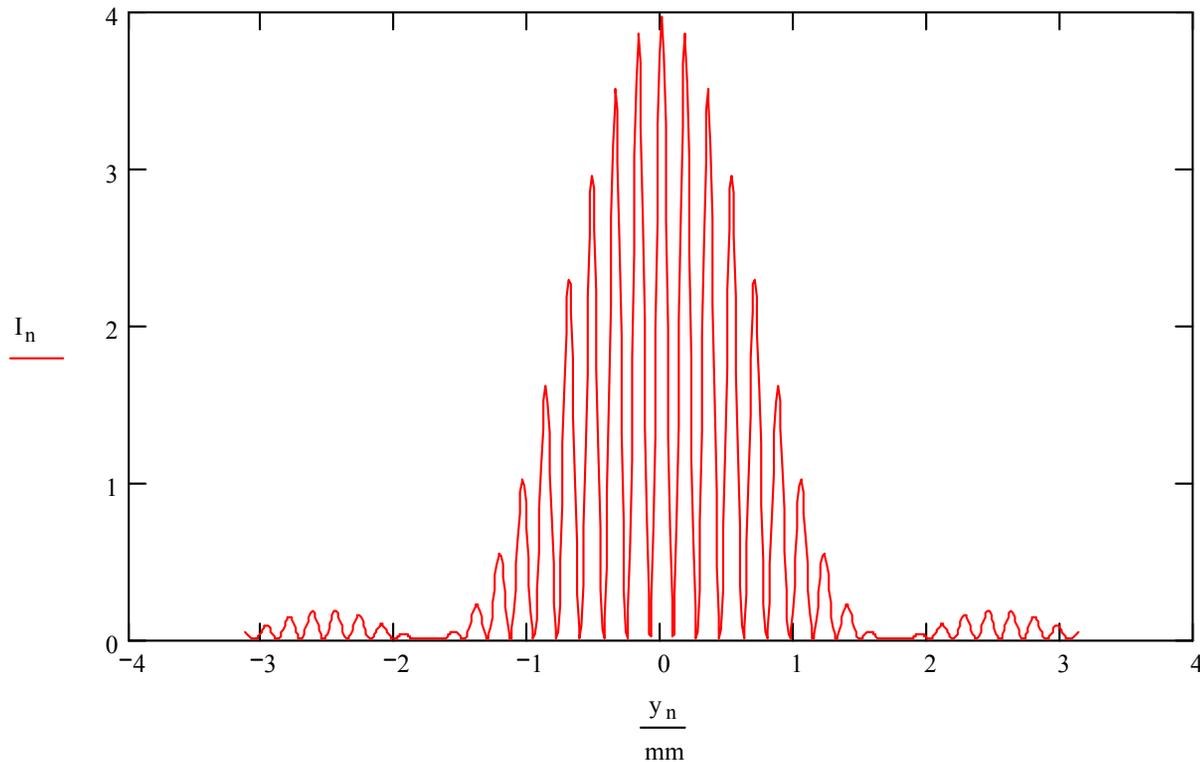
Individual  
slits

Interference  
between slits

Phase offset  
between slits



# Fringes of a Monochromatic Point Source



Fringe pattern of a monochromatic point source at 450 nm, using parameters for the PEP-II HER interferometer at SLAC.  $A_1 = A_2 = 1$ ,  $d = 5$  mm,  $a = 0.5$  mm.



# Diffraction from an Extended Source #1

- Replace point source at  $Y$  with a Gaussian: 
$$\frac{1}{\sqrt{2\pi}\sigma_0} \exp\left[-\frac{1}{2}\left(\frac{Y - Y_0}{\sigma_0}\right)^2\right]$$
- Source consists of independent electrons: Incoherent.
  - Integrate the intensity, not the electric field.
- Compare arguments:  $\text{sinc}^2(ka/2)$  versus  $\cos(kgd + \phi_0)$ 
  - Recall that: 
$$g = \frac{1}{z_{0s}} \left( Y + \frac{fy}{z_{fi}} \right) \sim \frac{1}{z_{0s}} \left( \sigma_0 + \frac{fy}{z_{fi}} \right)$$
  - For  $d=5$  mm,  $a=0.5$  mm,  $\lambda=450$  nm,  $\sigma_0=0.3$  mm,  $z_{0s}=10$  m:
    - $k\sigma_0 a / (2z_{0s}) = 0.105$  Small compared to zero of sinc at  $\pi$
    - $k\sigma_0 d / z_{0s} = 2.09$  Significant change in cosine phase



## Diffraction from an Extended Source #2

- We remove the sinc from the integral over the source, getting:

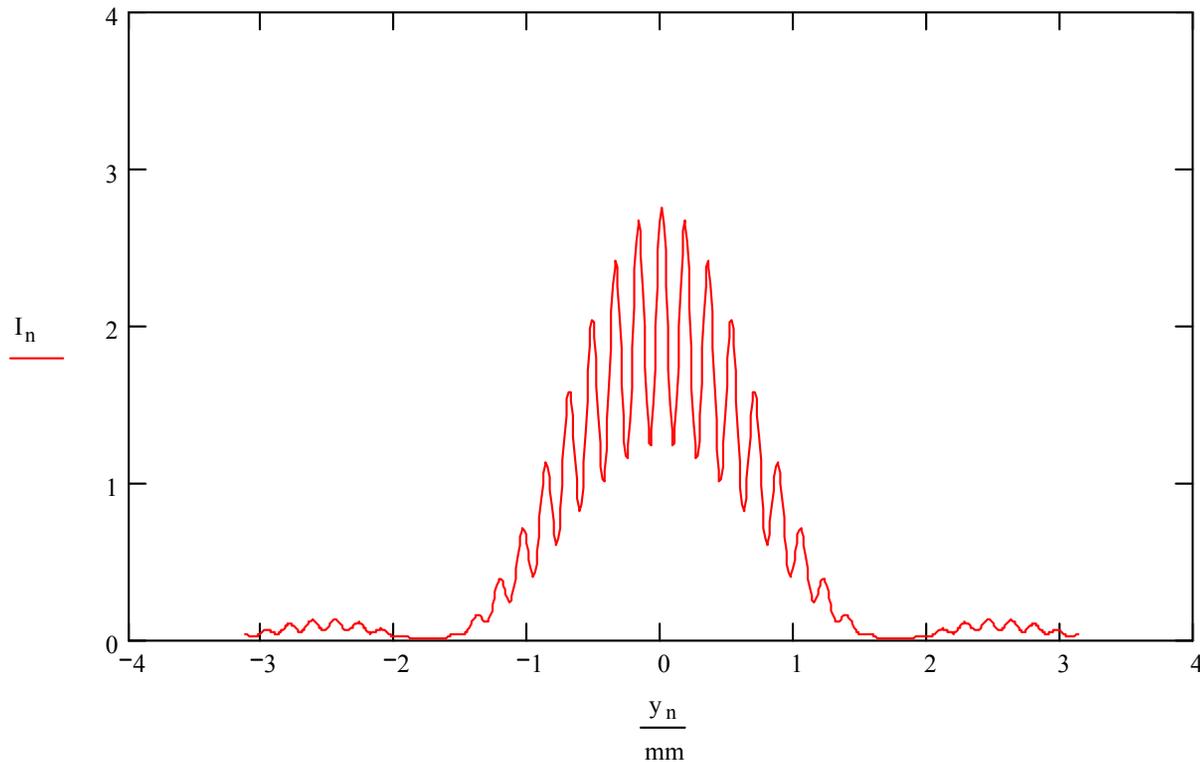
$$\begin{aligned} I(y, k) &= a^2 \text{sinc}^2 \left[ \frac{ka}{2z_{0s}} \left( Y_0 + \frac{fy}{z_{fi}} \right) \right] \\ &\quad \cdot \left\{ A_1 + A_2 + \frac{2\sqrt{A_1 A_2}}{\sqrt{2\pi\sigma_0}} \int \exp \left[ -\frac{1}{2} \left( \frac{Y - Y_0}{\sigma_0} \right)^2 \right] \cos \left[ \frac{kd}{z_{0s}} \left( Y + \frac{fy}{z_{fi}} \right) + \phi_0 \right] dY \right\} \\ &= a^2 \text{sinc}^2 \left[ \frac{kg_0 a}{2} \right] \left\{ A_1 + A_2 + 2\sqrt{A_1 A_2} \exp \left[ -\frac{1}{2} \left( \frac{k\sigma_0 d}{z_{0s}} \right)^2 \right] \cos(kg_0 d + \phi_0) \right\} \end{aligned}$$

where

$$g_0 = \frac{1}{z_{0s}} \left( Y_0 + \frac{fy}{z_{fi}} \right) = \frac{fy}{z_{0s} z_{fi}} - \theta_0 = \frac{y}{f + z_{fi}(1 - z_{sl}/f)} - \theta_0$$



# Fringes of an Extended Source



Fringe pattern of an extended source, with  $\sigma_0=0.2$  mm



# Quasi-Monochromatic Light #1

- Pass synchrotron light through a narrow Gaussian filter:  $\frac{1}{\sqrt{2\pi\sigma_k}} \exp\left[-\frac{1}{2}\left(\frac{k-k_0}{\sigma_k}\right)^2\right]$
- Compare arguments:  $\text{sinc}^2(kg_0a/2)$  versus  $\cos(kg_0d + \phi_0)$ 
  - Recall that:  $g_0 = \frac{y}{f + z_{fi}(1 - z_{sl}/f)} - \theta_0$ 
    - Essentially  $g_0$  is a scaled vertical coordinate with an offset  $\theta_0$ .
    - Compare effect of  $\sigma_k$  to an argument of  $\pi$ , where  $\text{sinc} = 0$ .
    - For  $\Delta\lambda = 30$  nm FWHM:
      - $\pi\sigma_k/k_0 = 0.09$       Small
- Again we can remove the sinc from the integration over the bandpass filter.



# Quasi-Monochromatic Light #2

$$I(y) = a^2 \text{sinc}^2 \left[ \frac{k_0 g_0 a}{2} \right] \cdot \left\{ A_1 + A_2 + \frac{2\sqrt{A_1 A_2}}{\sqrt{2\pi\sigma_k}} \int \exp \left[ -\frac{1}{2} \left( \frac{k - k_0}{\sigma_k} \right)^2 \right] \exp \left[ -\frac{1}{2} \left( \frac{k\sigma_0 d}{z_{0s}} \right)^2 \right] \cos(kg_0 d + \phi_0) dk \right\}$$

$$= a^2 \text{sinc}^2 \left[ \frac{k_0 g_0 a}{2} \right] \left\{ A_1 + A_2 \right.$$

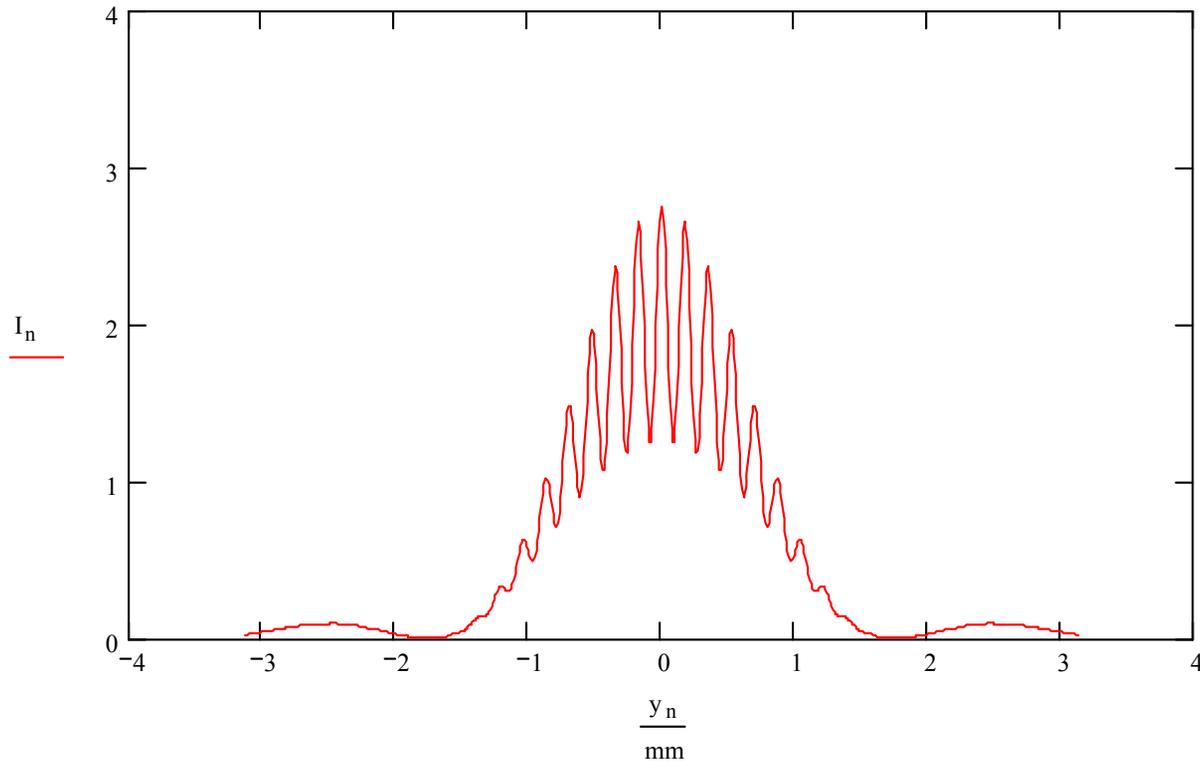
$$\left. + \frac{2\sqrt{A_1 A_2}}{\sqrt{1 + \left( \frac{\sigma_k \sigma_0 d}{z_{0s}} \right)^2}} \exp \left[ -\frac{\left( \frac{k_0 \sigma_0 d}{z_{0s}} \right)^2 + (\sigma_k g_0 d)^2}{2 \left[ 1 + \left( \frac{\sigma_k \sigma_0 d}{z_{0s}} \right)^2 \right]} \right] \cos \left[ \frac{k_0 g_0 d}{1 + \left( \frac{\sigma_k \sigma_0 d}{z_{0s}} \right)^2} + \phi_0 \right] \right\}$$

Beam size

Bandwidth



# Fringes with a Bandpass Filter



Fringe pattern using a Gaussian bandpass filter with a full width at half maximum (FWHM) of  $\Delta\lambda = 30$  nm.

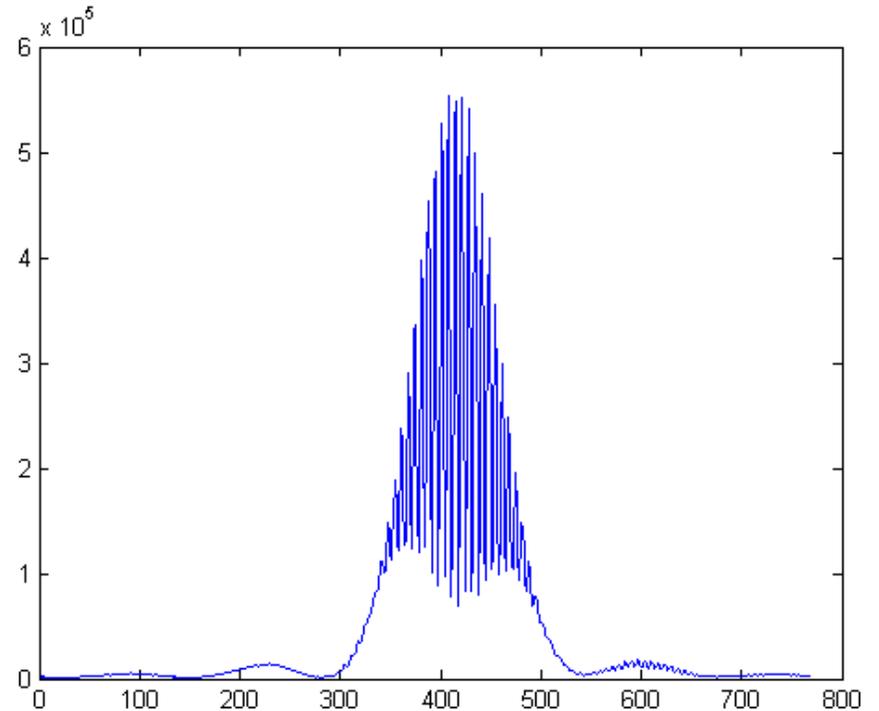
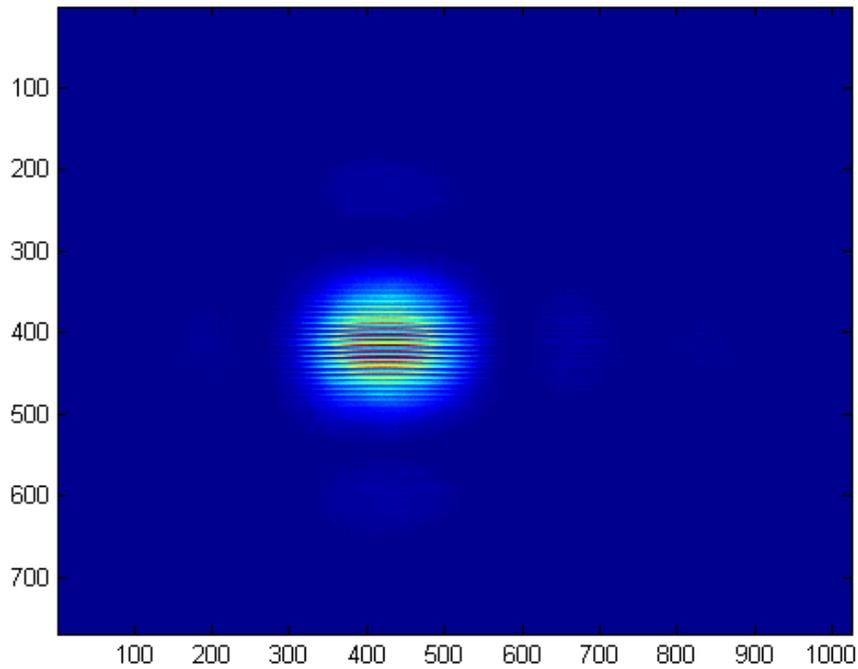


# Compare to van Cittert and Zernicke

- We previously looked at the derivation of van Cittert and Zernicke (VCZ). Is this approach the same?
- VCZ:
  - The “degree of coherence”  $\mu(A_1, A_2)$  between two apertures due to the finite source.
    - VCZ says that, for a narrow-band source, this expression resembles the diffraction pattern on the slit plane due to the source.
  - The intensity pattern on the camera is then determined from the single-aperture patterns and  $\mu$ .
- My approach changes the order, but reaches the same result:
  - First do the full calculation through two slits to the camera for a monochromatic point source.
  - Next include the finite size.
  - Finally add the narrow bandwidth.



# Interferometry on SPEAR-3





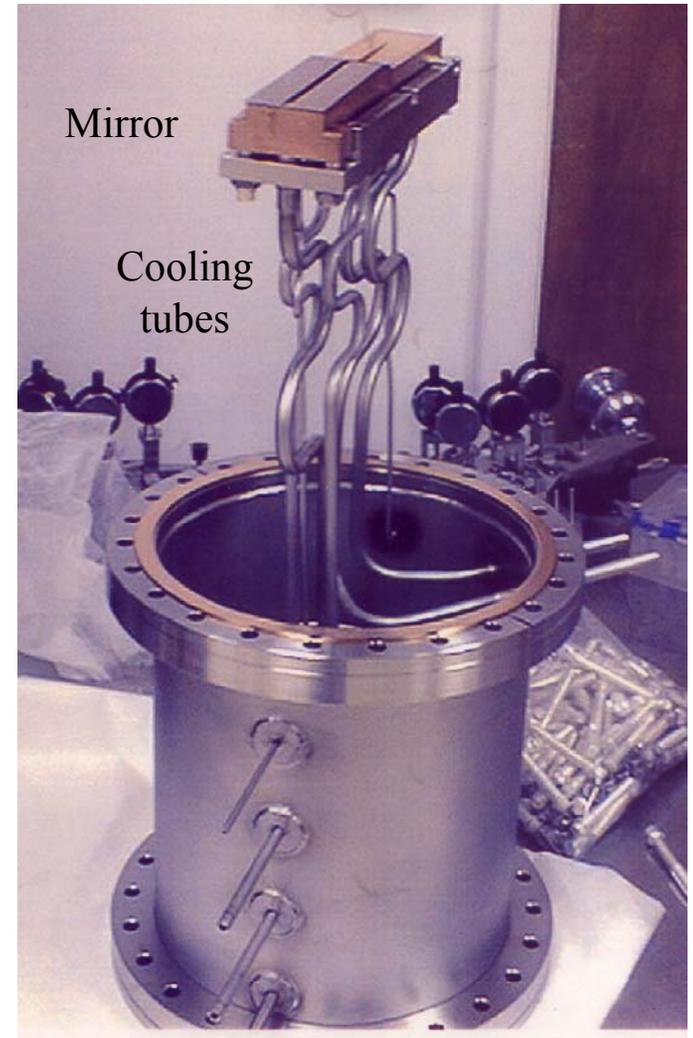
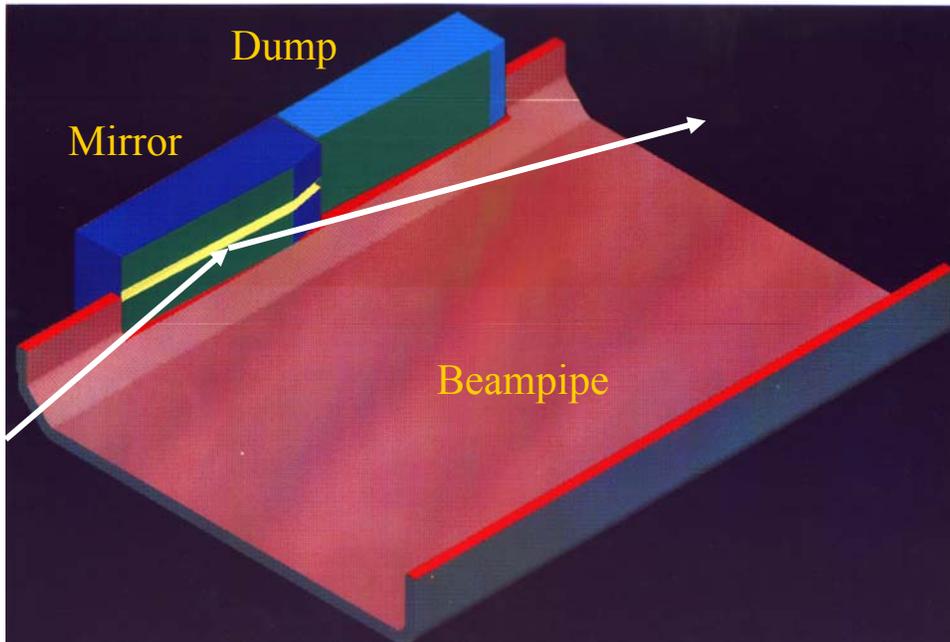
## Distortion of PEP's First Mirror

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- The first mirror in PEP-II takes a huge heat load, even with grazing incidence to spread out the heat.
  - Extensive (and stiff) stainless-steel water-cooling tubes on the rear add mechanical stress.
- A slot along the midplane of the mirror is meant to allow the narrow and hot x-ray fan to bypass the mirror and hit a separate dump.
  - Some folding of the mirror about the slot.
- Thermal and mechanical stresses reduce image quality and would decrease fringe contrast in an interferometer.



# First Mirror (M1) in the HER of PEP-II



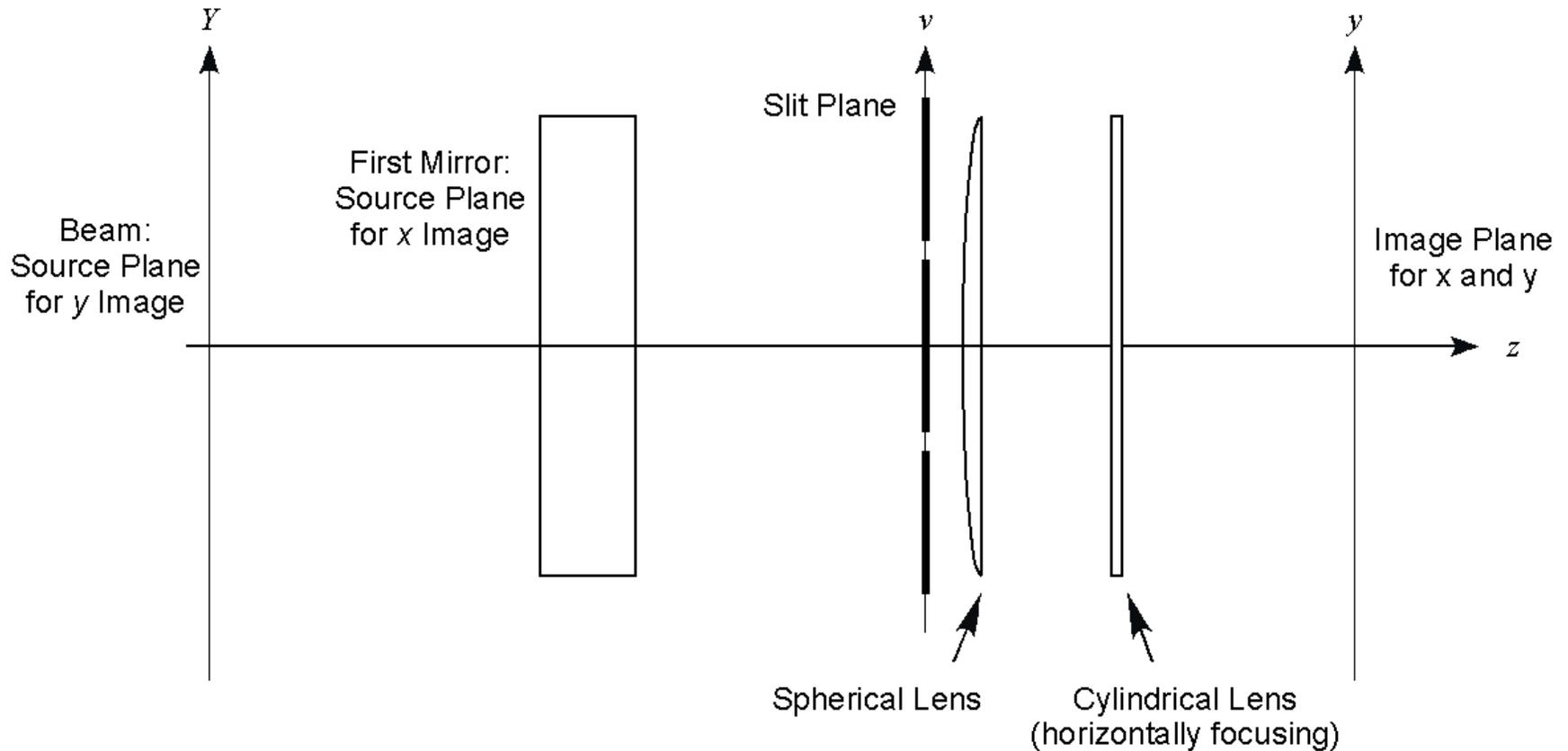


# Compensation with a Cylindrical Lens

- Interferometer slits pass light from two thin horizontal stripes along M1.
  - Little of M1's surface contributes...and we can reduce this more.
- Fringes from a vertical interferometer measurement form a series of parallel horizontal lines.
  - Beam size is calculated from the vertical intensity variation.
    - Beam is imaged through the slits onto the camera.
  - The direction along the stripe is less interesting.
    - Change the focal length horizontally to image M1, not the beam.
    - Insert a cylindrical lens to shorten the focal length.
    - Position along each stripe corresponds to an  $x$  coordinate of M1.
    - Computer selects  $x$  with best fringe visibility from the video.
- The interferometer uses only two small rectangles, selected for fringe quality, on M1's surface.

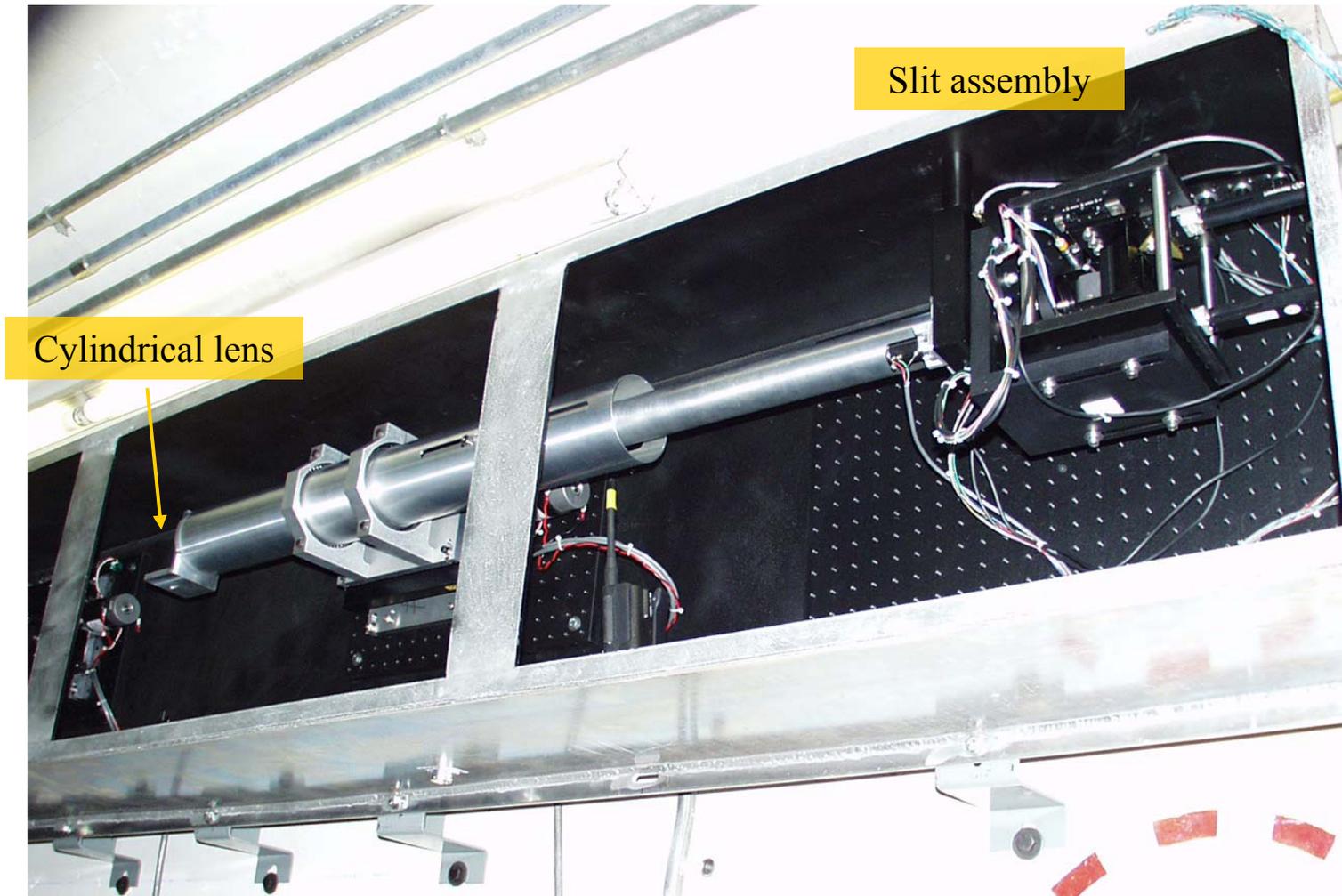


# Adding the Cylindrical Lens



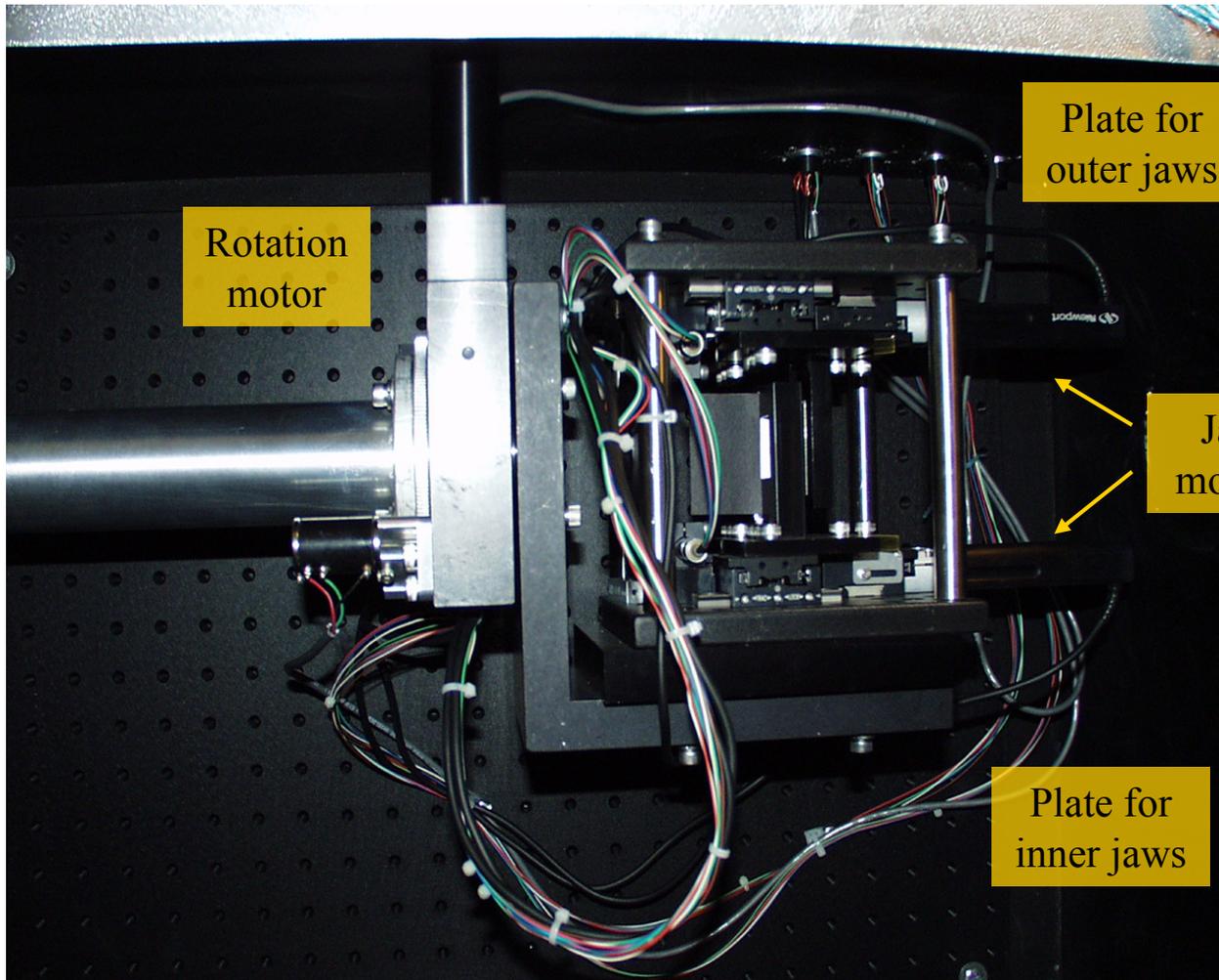


# LER Interferometer on Tunnel Wall





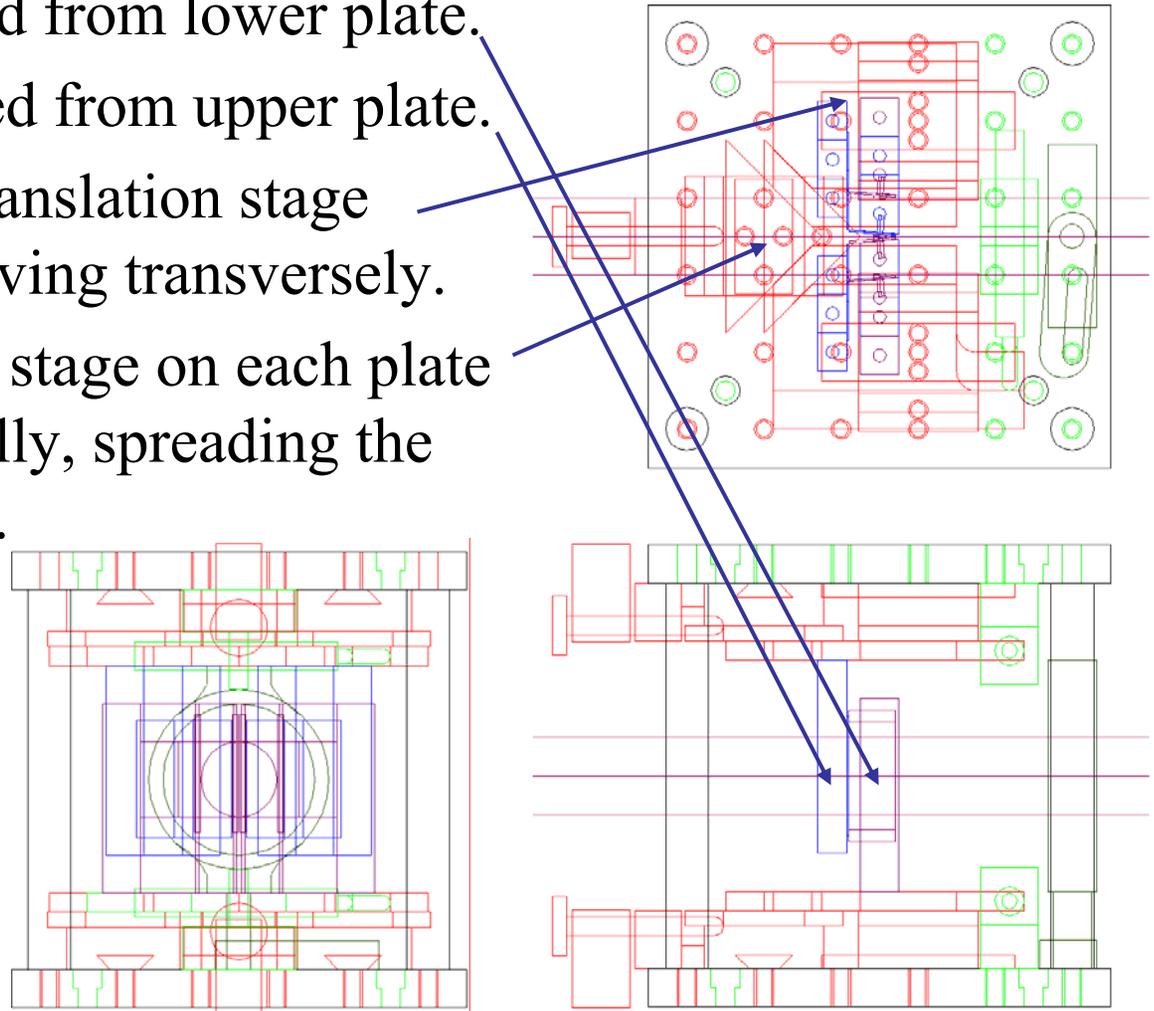
# Double-Slit Assembly





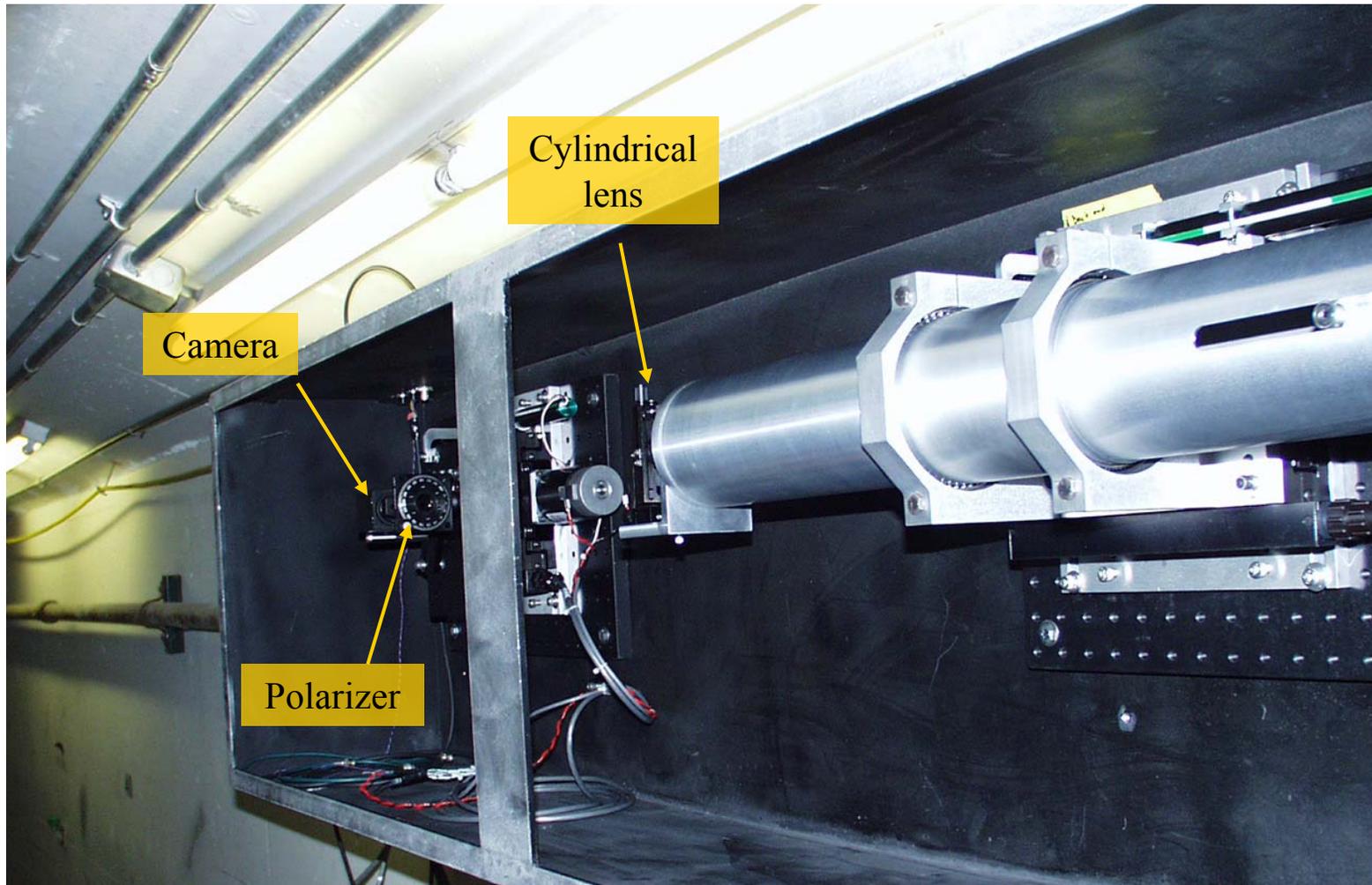
# Sketch of Slit Assembly

- Inner jaws mounted from lower plate.
- Outer jaws mounted from upper plate.
- Each jaw is on a translation stage with no motor, moving transversely.
- A third, motorized stage on each plate moves longitudinally, spreading the jaws with a wedge.



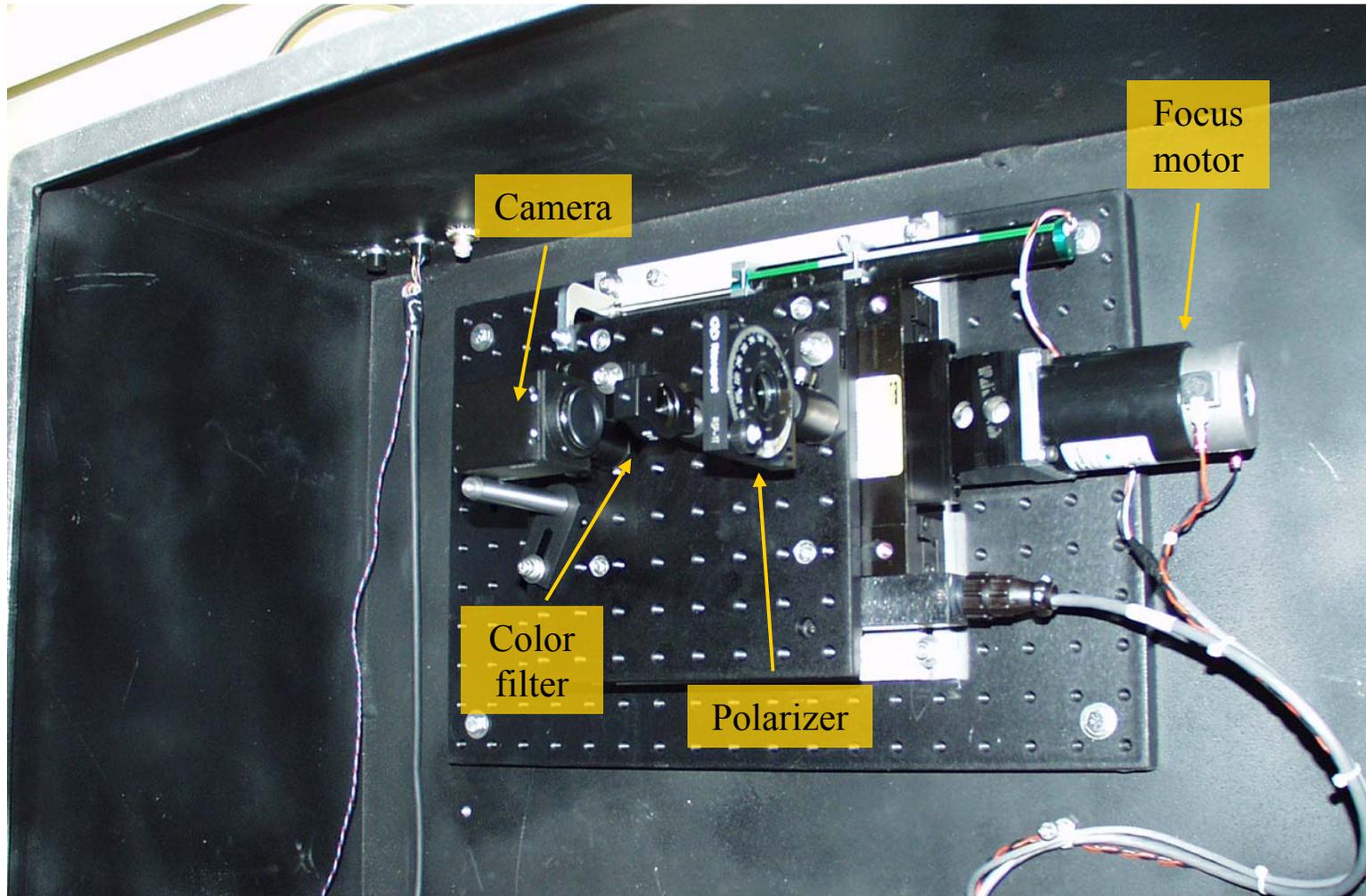


# Cylindrical Lens to Camera





# Polarizer, Filter, and Camera





# PEP-II Interferometer Software

